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ATTY. DOCKET NO.
60188-708

SERIAL NO.

10/713;217

APPLICANT
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(PTO-1449)

FILING DATE
November 17, 2003

GROUP
1756

U.S. PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		US			
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FOREIGN PATENT DOCUMENTS

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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
KTD		M. Switkes et al., "Immersion Lithography at 157nm", J. Vac. Sci. Technol. B 19(6), pp2353-2356, Nov/Dec, 2001

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